IN THE U.S. PATENT AND TRADEMARK OFFICE

Conf.: CHEN, I-Cheng et al Applicant:

Group: NEW Appl. No.:

Examiner: October 23, 2003 Filed:

NANOMETER SURFACE HTIW MATERIAL METHOD AND STRUCTURE For: FUNCTIONAL

MANUFACTURING THE SAME

PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 October 23, 2003

following preliminary amendments and remarks Sir: are respectfully submitted in connection with the above-identified application.

This amendment includes Amendments to the Specification and Remarks.